



## The Effect of Annealing Treatment on n-Cu<sub>2</sub>O Thin Film for Homostructure Application

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### ABSTRACT

This experiment is about fabrication of homojunction (n-type and p-type) based cuprous oxide (Cu<sub>2</sub>O) thin film by using electrodeposition method. The Cu<sub>2</sub>O thin film were deposited on fluorine doped tin oxide (FTO) substrates by using copper acetate based solution through potentiostatic electrodeposition method. The n-type Cu<sub>2</sub>O was fabricated at pH 6.3 with a fixed potential of -0.125V vs. Ag/AgCl and time deposition at 30 minutes. While, for p-type Cu<sub>2</sub>O was fabricated at pH 12.5 with fixed potential obtained from cyclic voltammetry measurement of -0.30V vs. Ag/AgCl for 2 hours. Annealing treatment was introduced to enhance the properties of the homostructure thin films. The quality of Cu<sub>2</sub>O thin film were studied and varied in term of annealing temperature and duration. Structural, morphological, optical and electrical properties were characterized using X-Ray Diffractometer (XRD), Field Emission Scanning Electron Microscopy (FE-SEM), Ultraviolet-visible Spectroscopy (UV-Vis) and Four Point Probe, respectively. Lastly, photoelectrochemical cell (PEC) measurement was studied to confirm the conduction type of each thin film and their photoresponse between as-deposited and annealed sample.

**Key words :** Electrodeposition, annealing treatment, Cu<sub>2</sub>O thin film.

### 1. INTRODUCTION

Solar cells devised used to convert sunlight into electricity by the photovoltaic effect. Photovoltaic effect is defined as the creation of voltage or electric current in a material upon exposure of light. This happen because when the light is incident upon a material surface, the electron in the valence band absorbs energy and become excited, making them jump to the conduction band and become free electrons [1]. All this while, silicon-based cells have been dominant material for So,

consume a lot of electricity [2]. researcher were trying to find others material and cuprous oxide (Cu<sub>2</sub>O) was one of them. With the material come in abundance, non-toxic and having low cost of production.

In order to fabricate high efficiency of solar cell, the heterojunction is produced this is proven by researches, that solar cells can be fabricated using the heterojunction process [3]. However, the greatest efficiency that manage to obtained by researcher was 5.38% [4] and its still considered as a small value. Thus, homojunction was introduced and has been proven that it was able to perform better than heterojunction in relevant applications [3]. Homojunction can be explain as the interface between two layers of similar semiconductor with equal energy band gap [5]. Which for this studied, the homostructure thin film consist a layer of n- and p-Cu<sub>2</sub>O fabricated by electrodeposition method. Many approaches have been explored to prepare Cu<sub>2</sub>O thin film. For example, thermal oxidation method [6], magnetron sputtering method [7], sol-gel process [8] and solvothermal method [5]. Among these method, electrodeposition was used since the properties of the thin film can be easily changed by altering the composition of the material. By fabricate homostructure thin film, the efficiency was believed increased. Annealing treatment was introduced to enhance the properties of the thin film. Thus, this research focus on the effects of based homostructure Cu<sub>2</sub>O thin film by manipulating the annealing duration and temperature through the annealing treatment on n-Cu<sub>2</sub>O thin film. The structural, morphological, optical and electrical characteristic of homostructure based Cu<sub>2</sub>O thin film was studied using X-ray Diffraction (XRD), Field emission-scanning electron microscope (FE-SEM), spectrometer (UV-Vis) and four point probe respectively.

### 2. EXPERIMENTAL PROCEDURES

Practically, the experiment has been carried out in the laboratory which required some apparatus and tools. Fluorine

doped thin oxide was used as the base substrate for deposition of  $\text{Cu}_2\text{O}$  thin films in a mixture solution of copper acetate. The mixture contain of 0.4M of copper acetate that act as precursor, 3M of lactic acid act as stabilizer and potassium hydroxide to control the pH of the solution. There are three electrode involved in electrodeposition process which were working, counter and reference electrode. Each electrode possess their own role in deposition process. Homostructure  $\text{Cu}_2\text{O}$  thin film was prepared at pH 6.3 for n-type and 12.5 for p-type, respectively. For n  $\text{Cu}_2\text{O}$  thin film, the bath temperature used was  $60^\circ\text{C}$  at 30 minutes duration with deposition potential of  $-0.125\text{ V vs. Ag/AgCl}$ .

In order to enhance the properties of the fabricated n- $\text{Cu}_2\text{O}$  thin film, the thin film were annealed with a certain temperature and different duration of annealing treatment. The annealing temperature was in the range of 200, 250 and  $300^\circ\text{C}$ . The duration of annealing treatment was varied in 20, 30, 40, 50 and 60 minutes. The preparation of n-  $\text{Cu}_2\text{O}$  thin film which not involved any annealing process called as-deposited was fabricated in order to compare the performance between the samples. Prior to the deposition of p- $\text{Cu}_2\text{O}$  thin film, cyclic voltammetry measurement was carried out to determine the suitable deposition potential of p- $\text{Cu}_2\text{O}$  thin film. Then, p-  $\text{Cu}_2\text{O}$  was deposited onto the n- $\text{Cu}_2\text{O}$  /FTO substrate. Table 1 shown the fixed deposition parameter and Table 2 various annealing process parameter of each samples, respectively.

For characterization, XRD, FE-SEM, UV-Vis and four point probe was used to analyse the structural, morphological, optical and electrical properties of the thin film. Photoelectrochemical cell (PEC) measurement was carried out to confirm the conduction type of the homostructure  $\text{Cu}_2\text{O}$  thin film.

**Table 1:** Deposition parameter.

Deposition parameter		
	n- $\text{Cu}_2\text{O}$	p- $\text{Cu}_2\text{O}$
Potential (V vs. Ag/AgCl)	-0.125	-0.30
Bath temperature ( $^\circ\text{C}$ )	60	40
pH value	6.3	12.5
Deposition Time (min)	30	120

**Table 2:** Annealing parameter.

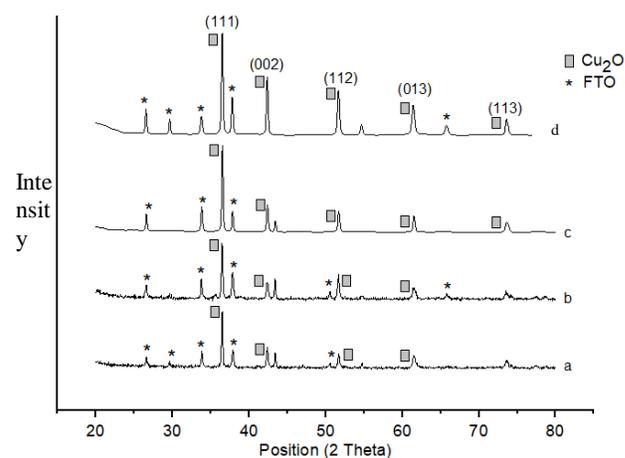
Annealing temperature ( $^\circ\text{C}$ )	Annealing time (min)
200	20, 30, 40, 50 and 60
250	20, 30, 40, 50 and 60
300	20, 30, 40, 50 and 60

### 3. EXPERIMENTAL RESULT

#### 3.1 The Effect of Annealing Treatment on Annealed N- $\text{Cu}_2\text{O}$ Thin Film

The n-  $\text{Cu}_2\text{O}$  thin film with the addition of annealing treatment with variety of temperature and duration of annealed were compared. The structural state of the annealed n-  $\text{Cu}_2\text{O}$  thin film on FTO substrate were characterized by using XRD,

respectively. From Figure 1, the XRD pattern for all the samples were observed. The peak labelled with grey square is refer to  $\text{Cu}_2\text{O}$  material. The peaks with  $2\theta$  values of 29.65, 36.47, 42.37, 61.74 and 73.65 corresponding to (110), (111), (200), (220) and (311) crystal planes of  $\text{Cu}_2\text{O}$ , respectively. Hence, the peak list of  $\text{Cu}_2\text{O}$  material are shown in Table 3. The most dominant orientation was (111) plane at position  $2\theta$  of  $36.47^\circ$  which could be determined by referring to the highest peak in the XRD pattern. The results can be related with previous research which mentioned that the dominant orientation of (111) at  $36.47^\circ$  of  $\text{Cu}_2\text{O}$  material [9]. The (111) was the preferred orientation because of the molecule absorption has been performed onto this plane and the surface of the plane is non-polarized with the most stable surface when pairing with Lewis acid-basic pairs [10]. For annealed n-  $\text{Cu}_2\text{O}$  thin film, there was a negligible different in the XRD pattern as compared to as-deposited sample. As an example to that, the peak of annealed n-  $\text{Cu}_2\text{O}$  thin film did not shift and stay at their position of  $2\theta$ . The similar research has reported by Kim, T.G and his co-worker which proved that annealing treatment do not affect the position peak of  $2\theta$  [11]. Among those samples, n-  $\text{Cu}_2\text{O}$  thin film at temperature of  $200^\circ\text{C}$  with duration of 60 minutes exhibited higher peak of intensity compared to others. This leads to the increment of the crystallinity of the material. Hence, the sample was differed with n-  $\text{Cu}_2\text{O}$  thin film at an annealed duration of 40 minutes with temperature of  $300^\circ\text{C}$  since it exhibit the lowest intensity of the peak. This is due to the peak has a kind of mixed  $\text{Cu}_2\text{O}$  - $\text{CuO}$  phase as the samples has been annealed due to heating process in which the  $\text{Cu}_2\text{O}$  will be converted to  $\text{CuO}$  in the presence of oxygen [12]. Another pattern that can be interpreted from the figure is, the increasing in annealed temperature leads to decreasing in annealed duration in order to improve to the crystallinity of the material. The relationship that can be interpreted from this result is a low temperature of annealing required a longer duration of process and vice versa.



**Figure 1:** XRD pattern for (a) as-deposited and annealed n- $\text{Cu}_2\text{O}$  thin at annealed duration of (b) 20, (c) 30, (d) 40, (e) 50 and (f) 60 minutes, respectively

The morphological surface of the annealing n-  $\text{Cu}_2\text{O}$  thin film was studied with FE-SEM instrument. Figure 2 shows the FE-SEM image of (a) as-deposited, and optimize Parameter of annealing duration and temperature,

**Table 3:** Corresponding plane for  $\text{Cu}_2\text{O}$  reflection peaks

2 Theta (Degree)	Phase [h k l]
29.65	(110)
36.47	(111)
42.37	(200)
61.74	(220)
73.65	(311)

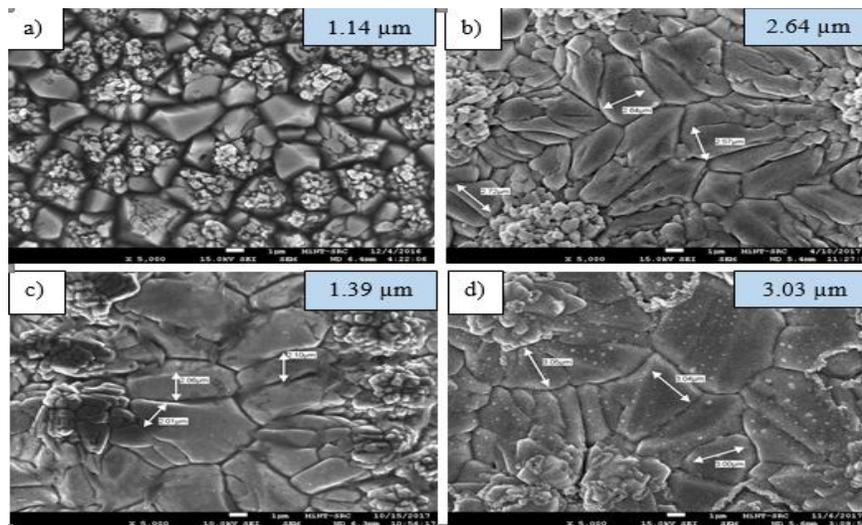
The triangular and pyramidal shapes of the  $\text{Cu}_2\text{O}$  were observed according to their corresponding annealed time. The as-deposited n-  $\text{Cu}_2\text{O}$  thin film was examined to have small grain as an additional structure to the material. As annealing treatment was introduced, the samples showed a varying changes in reference to the amount of small grain structure. Based on the previous study, the enhancement of the morphological properties was observed by the decrement of the small grains after annealing treatment [6]. The triangular and pyramidal shapes of the  $\text{Cu}_2\text{O}$  were observed according to their corresponding annealed time. The as-deposited n-  $\text{Cu}_2\text{O}$  thin film was examined to have small grain as an additional structure to the material. As annealing treatment was introduced, the samples showed a varying changes in reference to the amount of small grain structure. Based on the previous study, the enhancement of the morphological properties was observed by the decrement of the small grains after annealing treatment [6]. It was believed that the small grain in the sample agglomerated to form further bunches of larger grain but when the temperature was too high, it induced larger amount of stress in  $\text{Cu}_2\text{O}$  thin film. However, when the

annealing duration and temperature must be taken into account to produce a better performance of  $\text{Cu}_2\text{O}$  thin film. Hence, 60 minutes of annealed duration with  $200^\circ\text{C}$  annealed temperature was the optimal parameter for n-  $\text{Cu}_2\text{O}$  thin film.

### 3.2 Construction of $\text{Cu}_2\text{O}$ Based Homostructure

Cyclic Voltammetry measurement (CV) was performed prior to the deposition of p-type  $\text{Cu}_2\text{O}$  (p-  $\text{Cu}_2\text{O}$ ) thin film. CV measurement applied to identify the reaction mechanism of n-  $\text{Cu}_2\text{O}$  thin film by obtaining a suitable and optimum potential for deposition of p-  $\text{Cu}_2\text{O}$  onto n-  $\text{Cu}_2\text{O}$  /FTO. During the process of CV measurement, there are two reactions occurred which are oxidation and reduction reaction. However, in this study, only reduction reaction is taken into account. Figure 3 shows the potential range determination of  $\text{Cu}_2\text{O}$  using CV measurement at pH 12.5 with a water bath temperature of  $40^\circ\text{C}$ . Since the optimum parameter for annealed n-  $\text{Cu}_2\text{O}$  thin film with annealed temperature of  $200^\circ\text{C}$  of 60 minutes duration, a CV measurement was performed on the optimized thin film to obtain the suitable potential deposition for p-  $\text{Cu}_2\text{O}$  thin film. The voltammogram range was set up between 0.5 and -1.0 vs Ag/AgCl at a scan rate of 5mV/s. From the CV measurement of the optimized thin film, two reduction at cathodic regions were observed in the graph of Figure 3. The first regions occurred from -0.2V to -0.35V vs. Ag/AgCl. The first peak was referred to the reduction reaction of  $\text{Cu}^{2+}$  to  $\text{Cu}^+$  and hence to  $\text{Cu}_2\text{O}$ . Then, the second peak belongs to reduction reaction of  $\text{Cu}^{2+}$  to Cu which can be said as a metallic copper formation. Then, the deposition potential of -0.30V vs Ag/AgCl was chosen as the optimum potential for this homostructure.

For structural properties, the graph showed peaks detected at 29.65, 36.47, 42.37, 61.74 and 73.65 which corresponding to  $\text{Cu}_2\text{O}$  plane orientation at (110), (111), (200), (220) and

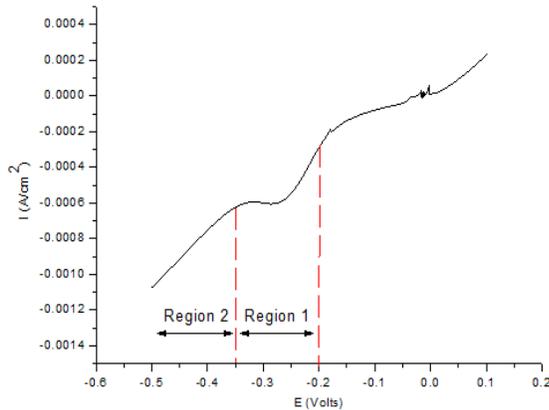


**Figure 2:** FE-SEM images of surface morphology of n- $\text{Cu}_2\text{O}$  thin film (a) As-deposited and at annealed duration of (b) 60 mins at temperature of  $200^\circ\text{C}$ , (c) 50 mins at temperature of  $250^\circ\text{C}$ , (d) 40 mins at temperature of  $300^\circ\text{C}$ , respectively

annealing temperature reached  $300^\circ\text{C}$  and above, the morphology of the material as well as structural properties was obviously change. This change leads to the degradation performance of the material. Thus, by controlling the

(311), respectively. Obviously, the (111) plane orientation presented a highest intensity among other peak which make it as the preferred orientation of  $\text{Cu}_2\text{O}$  material. The result indicated that more crystallize grain was obtained at the

preferred orientation plane. From Figure 4, the increment of  $\text{Cu}_2\text{O}$  peaks was observed indicating the p- $\text{Cu}_2\text{O}$  was successfully fabricated on n- $\text{Cu}_2\text{O}$ /FTO substrate. Furthermore, both acidic and basic electrolyte will lead to a

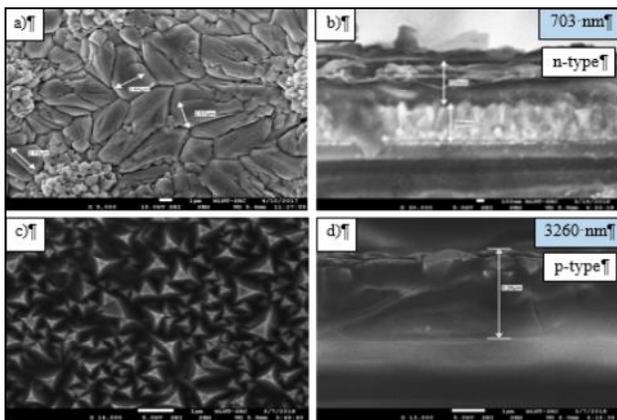


**Figure 3:** Potential range determination of  $\text{Cu}_2\text{O}$  at pH 12.5 with a fixed temperature of  $40^\circ\text{C}$

stable environment for growth of  $\text{Cu}_2\text{O}$  thin film during electrodeposition process [13].

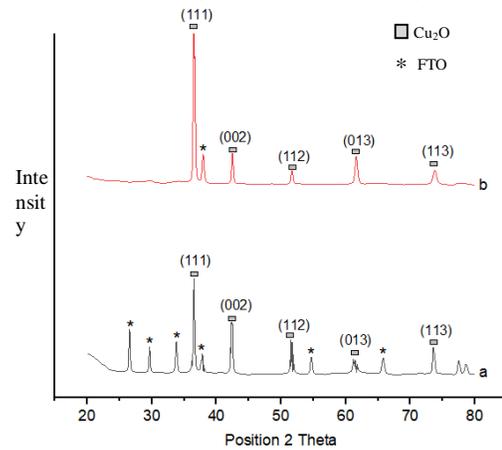
These statement can answered the possibility of obtaining the fully grown  $\text{Cu}_2\text{O}$  material onto FTO glass substrate which directly help the process of molecule absorption at the preferred orientation of (111).

For morphological properties, there are slightly different in term of their morphology structure before and after fabricating the p-  $\text{Cu}_2\text{O}$  thin film. The size structure of n- $\text{Cu}_2\text{O}$  material that was produced in a bigger and larger surface is compared to p-  $\text{Cu}_2\text{O}$ . However, even the pyramidal triangular shape of p-  $\text{Cu}_2\text{O}$  are considered as small in size, but it is more compact and the surface is more covered. In addition, an identical condition which can be related to previous researcher which stated that the acidic electrolyte with pH 6.5 is used to grow an n-  $\text{Cu}_2\text{O}$  did not disrupt the layer of p-  $\text{Cu}_2\text{O}$  or degrade the quality of the thin film [13]. Not only that, the morphology of the homostructure sample seems to grow with better and well defined pyramidal triangular shape. By implementing annealing treatment on n- $\text{Cu}_2\text{O}$  thin film with addition of p-  $\text{Cu}_2\text{O}$  deposited, more uneven shaped grain agglomerate to form crystallite grains



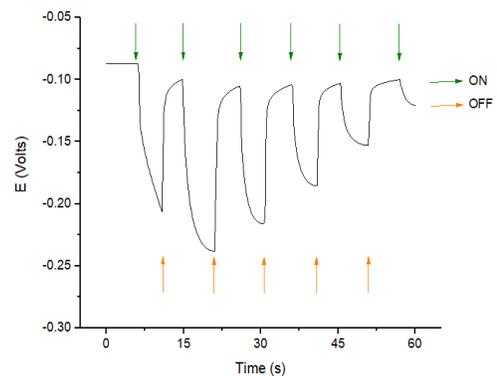
**Figure 5:** FE-SEM images of (a) surface (b) cross sectioned of optimize annealed n- $\text{Cu}_2\text{O}$  and (c) surface (d) cross sectioned of p- $\text{Cu}_2\text{O}$  onto optimize annealed n- $\text{Cu}_2\text{O}$ /FTO thin film

and the surface mobility enhanced indirectly [14].

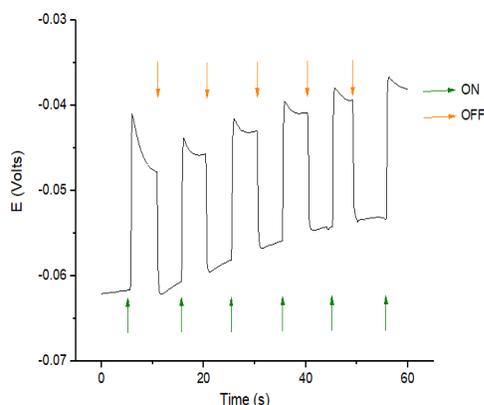


**Figure 4:** XRD pattern of electrodeposited (a) annealed n-  $\text{Cu}_2\text{O}$  (b) p- $\text{Cu}_2\text{O}$  on n-  $\text{Cu}_2\text{O}$  /FTO thin films

The PEC measurement was carried out to verify the conduction type of  $\text{Cu}_2\text{O}$  material whether it is successful deposition of p-  $\text{Cu}_2\text{O}$  or n-  $\text{Cu}_2\text{O}$ . The mechanism of PEC measurement can be explained by, when the thin film was illuminated with light, the electron-hole pairs were generated in the space charge region of the surface  $\text{Cu}_2\text{O}$  thin film which were then being separated by the built-in electric field. This mechanism leads to the formation of photocurrents. The two conduction of  $\text{Cu}_2\text{O}$  material which are n-type and p-type have an opposite photocurrents where the former is anodic and the latter is cathodic [15]. Based on Figure 6, the optimum annealed n-  $\text{Cu}_2\text{O}$  thin film which at temperature of  $200^\circ\text{C}$  with annealed duration of 60 minutes was tested to examine the conduction type of  $\text{Cu}_2\text{O}$  material. The result shows that the sample with a pH value of 6.3 was confirmed as n-  $\text{Cu}_2\text{O}$  thin film. This finding can be explained as when light illuminates an n-type semiconductor, the absorbed light generates carriers that cause a negative shift of Fermi level potential vs Ag/AgCl [13]. However,  $\text{Cu}_2\text{O}$  thin film in a basic electrolyte at pH 12.5 displays a positive shift under illumination, which reflects the p-type character of the  $\text{Cu}_2\text{O}$  thin film. These photocurrent results consistent with CV measurement and demonstrated that the pH of electrolyte can control the conduction type in electrodeposited  $\text{Cu}_2\text{O}$  thin film [16].



**Figure 6:** Open circuit photovoltage measured as a function of time under pulse irradiation for As-deposited n- $\text{Cu}_2\text{O}$  thin film



**Figure 7:** Open circuit photovoltage measured as a function of time under pulse irradiation for p-Cu<sub>2</sub>O thin

#### 4. CONCLUSION

This project is conducted to study the effect of annealing treatment parameter on n-Cu<sub>2</sub>O thin film for homostructure application by using electrodeposition method. The homostructure thin film was formed by fabricating two types of Cu<sub>2</sub>O layers. Firstly, the n-Cu<sub>2</sub>O was deposited onto FTO substrate. Then, the sample undergoes annealing treatment for different temperature and certain duration of annealed. Characterization process was carried out to determine the optimum annealing parameter for annealed n-Cu<sub>2</sub>O thin film. Next, deposition of p-Cu<sub>2</sub>O occurred onto the optimized annealed n-Cu<sub>2</sub>O /FTO substrate. The properties of the thin film was improved after annealing with certain optimum parameter with addition of p-Cu<sub>2</sub>O deposited (based homostructure). The structural properties of n-Cu<sub>2</sub>O were analysed and all sample possessed (111) preferred orientation. Among these samples, annealed n-Cu<sub>2</sub>O thin film at temperature of 200°C with duration of 60 minutes shows a highest intensity of the peak at preferred orientation of (111). For morphological characterization, the properties of the samples Cu<sub>2</sub>O thin exhibited pyramid triangular shapes. In addition, the morphology of the material was change as the annealed parameter was varied. However, annealed n-Cu<sub>2</sub>O thin film at temperature of 200°C with duration of 60 minutes shows a better morphology among all due to the minimize present of the small grain in the FE-SEM image. From CV measurement, the optimum deposition potential chosen was -0.30 V vs Ag/AgCl. Next, the p-Cu<sub>2</sub>O thin film was fabricated on an optimized annealed n-Cu<sub>2</sub>O thin film. Characterization process occurred to determine the properties of the material. For XRD analysis, 36.45° shows the highest peak of the intensity at orientation plane of (111) which indicates a higher crystallinity of the p-Cu<sub>2</sub>O thin film. The morphological properties exhibited pyramidal triangular shape which are considered to be Cu<sub>2</sub>O structure. Besides, the negative and positive shift of PEC measurement also indicated that the pH value 6.3 and 12.5 were n-Cu<sub>2</sub>O and p-Cu<sub>2</sub>O thin film.

As for the conclusion, the Cu<sub>2</sub>O based homostructure thin film was successfully fabricated from the acid-based copper acetate based solution by electrodeposition method. The

optimum parameters of n-Cu<sub>2</sub>O and p-Cu<sub>2</sub>O thin film were obtained by characterizing each sample which all the results were supported by previous research findings. However, further investigation and research need to be carried out to obtain a more successful fabrication on Cu<sub>2</sub>O homostructure thin film.

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